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(54) **FLUID EJECTION DEVICE**

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(Continued)

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See application file for complete search history.

(56) **References Cited**

U.S. PATENT DOCUMENTS

7,401,910 B2 7/2008 Silverbrook
8,752,946 B2 6/2014 Wells et al.
(Continued)

FOREIGN PATENT DOCUMENTS

CN 102971150 A 3/2013
CN 102985261 A 3/2013
(Continued)

OTHER PUBLICATIONS

Brand new wide-format inkjet printhead from Xaar. http://www.printanddigitalcommunicationworld.com/brand-new-wide-format-inkjet-printhead-from-xaar/ Jul. 3, 2014.

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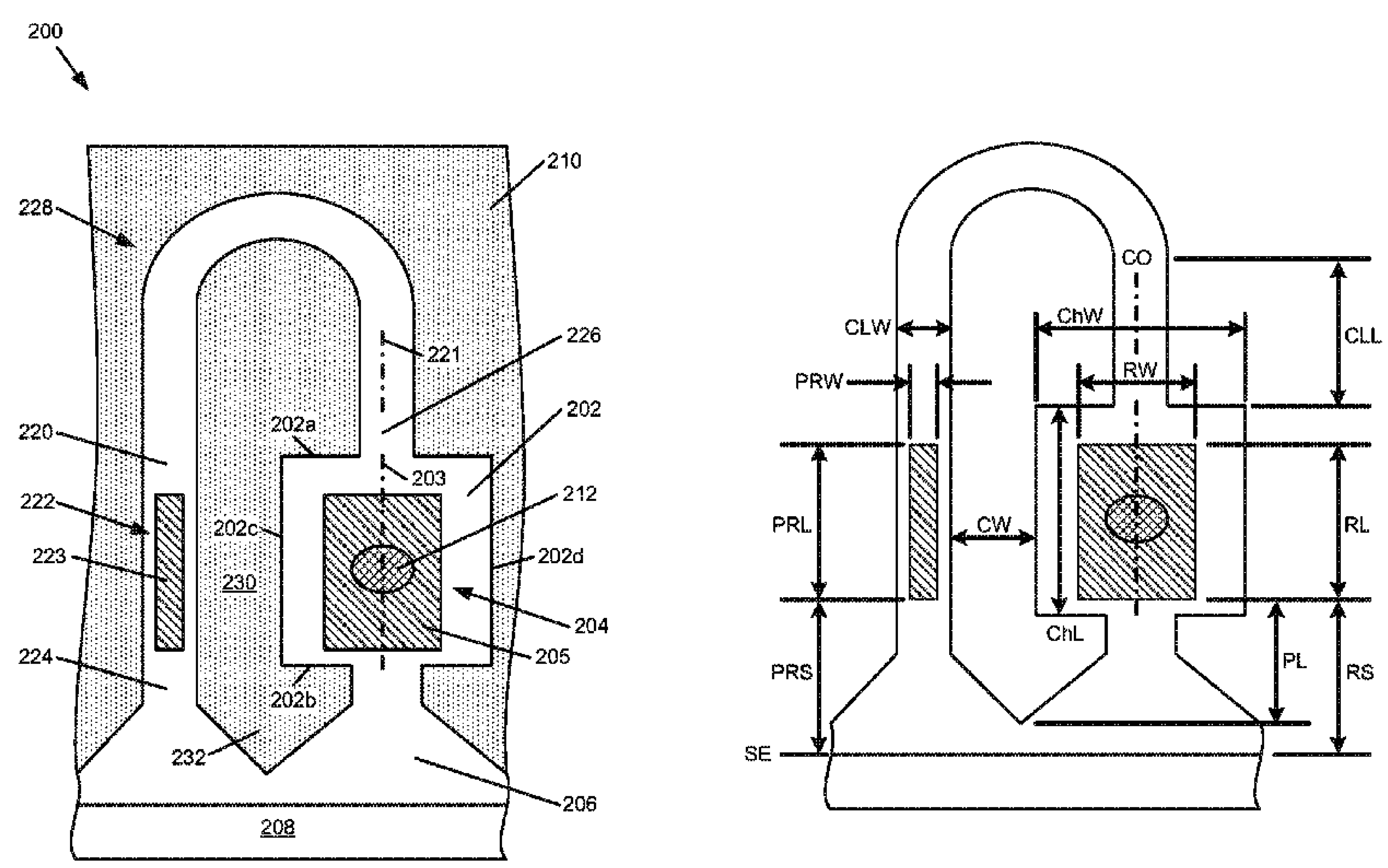
(57) **ABSTRACT**

A fluid ejection device includes a fluid slot, a fluid ejection chamber communicated with the fluid slot, a drop ejecting element within the fluid ejection chamber, a fluid circulation channel communicated at one end with the fluid slot and communicated at another end with the fluid ejection chamber, a fluid circulating element within the fluid circulation channel, and a channel wall separating the fluid ejection chamber and the fluid circulation channel. The fluid circulation channel includes a channel loop, and a width of the channel wall is based on a width of the channel loop and a width of the fluid ejection chamber.

20 Claims, 6 Drawing Sheets



(52) **U.S. Cl.**
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(56) **References Cited**

U.S. PATENT DOCUMENTS

8,814,293 B2		8/2014	Strunk et al.
2010/0177133 A1*		7/2010	Makishima B41J 2/14209 347/10
2011/0128335 A1		6/2011	Von Essen et al.
2011/0181674 A1		7/2011	Kang et al.
2013/0155135 A1		6/2013	Govyadinov et al.
2013/0278688 A1		10/2013	Bibl
2013/0321507 A1		12/2013	Mardilovich et al.
2014/0204148 A1		7/2014	Ge et al.
2015/0049141 A1*		2/2015	Taff B41J 2/1404 347/54

FOREIGN PATENT DOCUMENTS

WO	WO2013130039	9/2013
WO	WO2014003772	1/2014

* cited by examiner

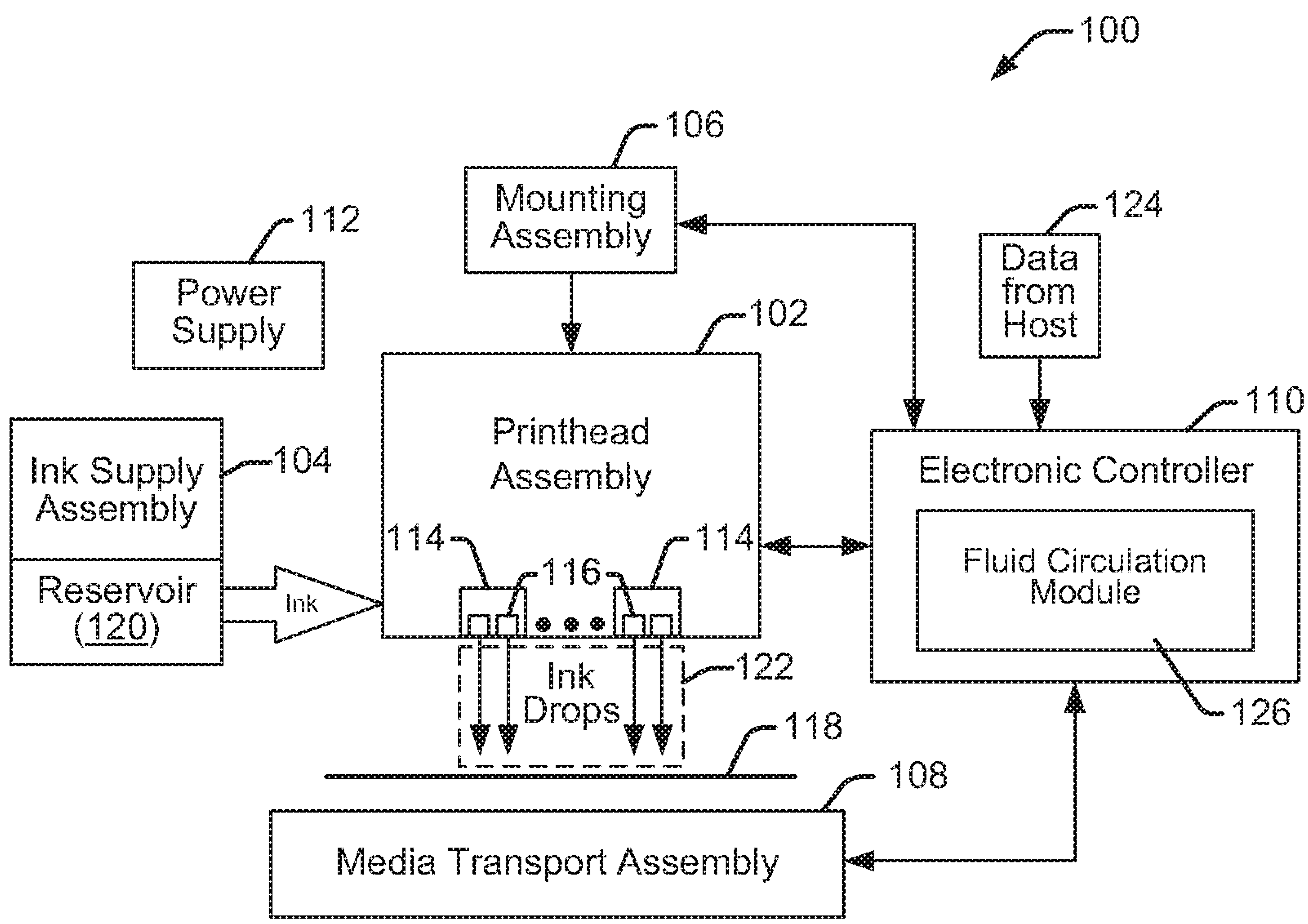
100
106
Mounting Assembly
112
Power Supply
124
Data from Host
102
Printhead Assembly
110
Electronic Controller
Fluid Circulation Module
Ink Supply Assembly
104
Reservoir (120)
Ink
114
116
114
122
Ink Drops
126
118
108
Media Transport Assembly

FIG. 1

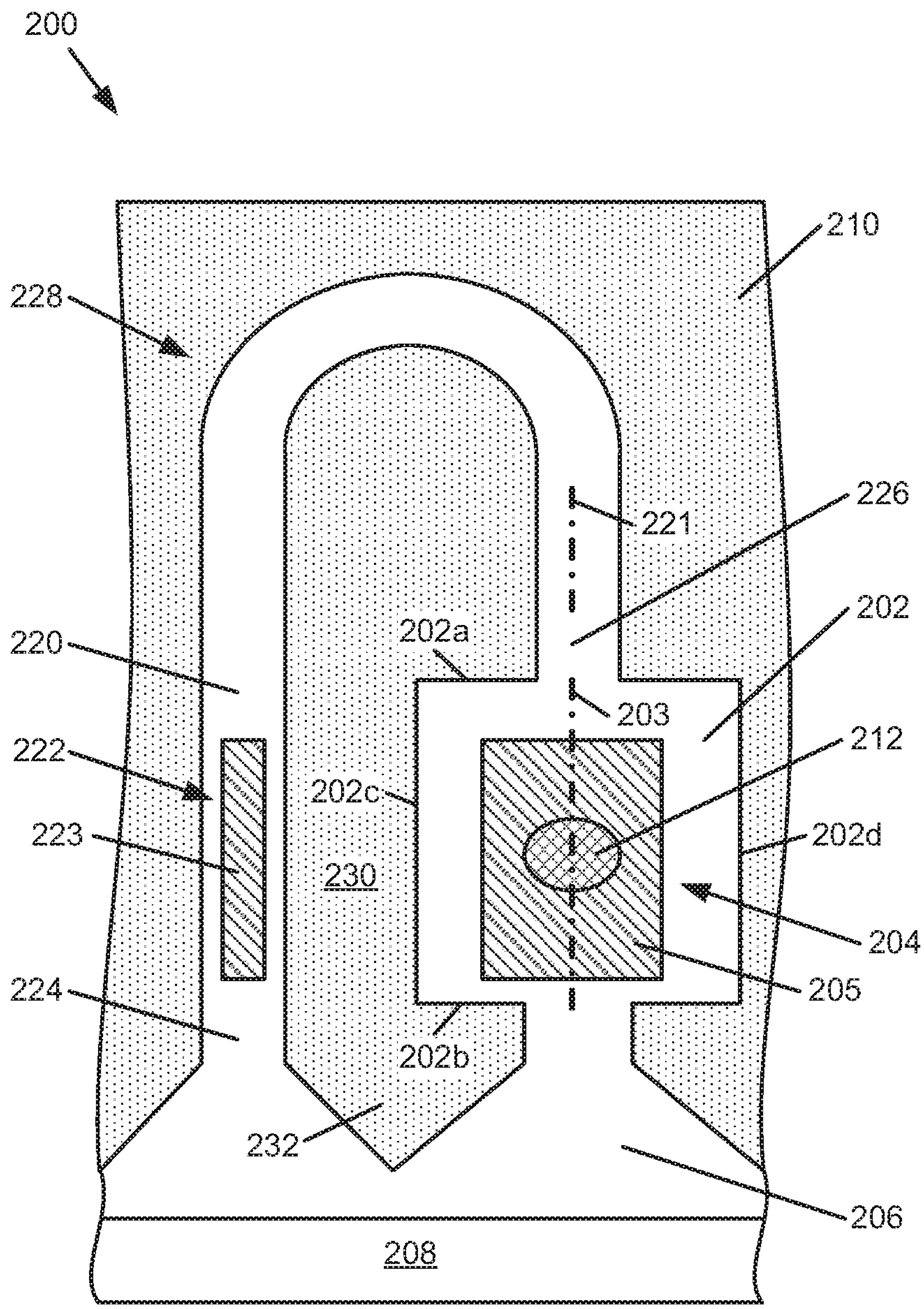
200
210
228
226
221
202
202a
220
203
212
222
202c
202d
223
230
204
205
224
202b
232
206
208

FIG. 2A

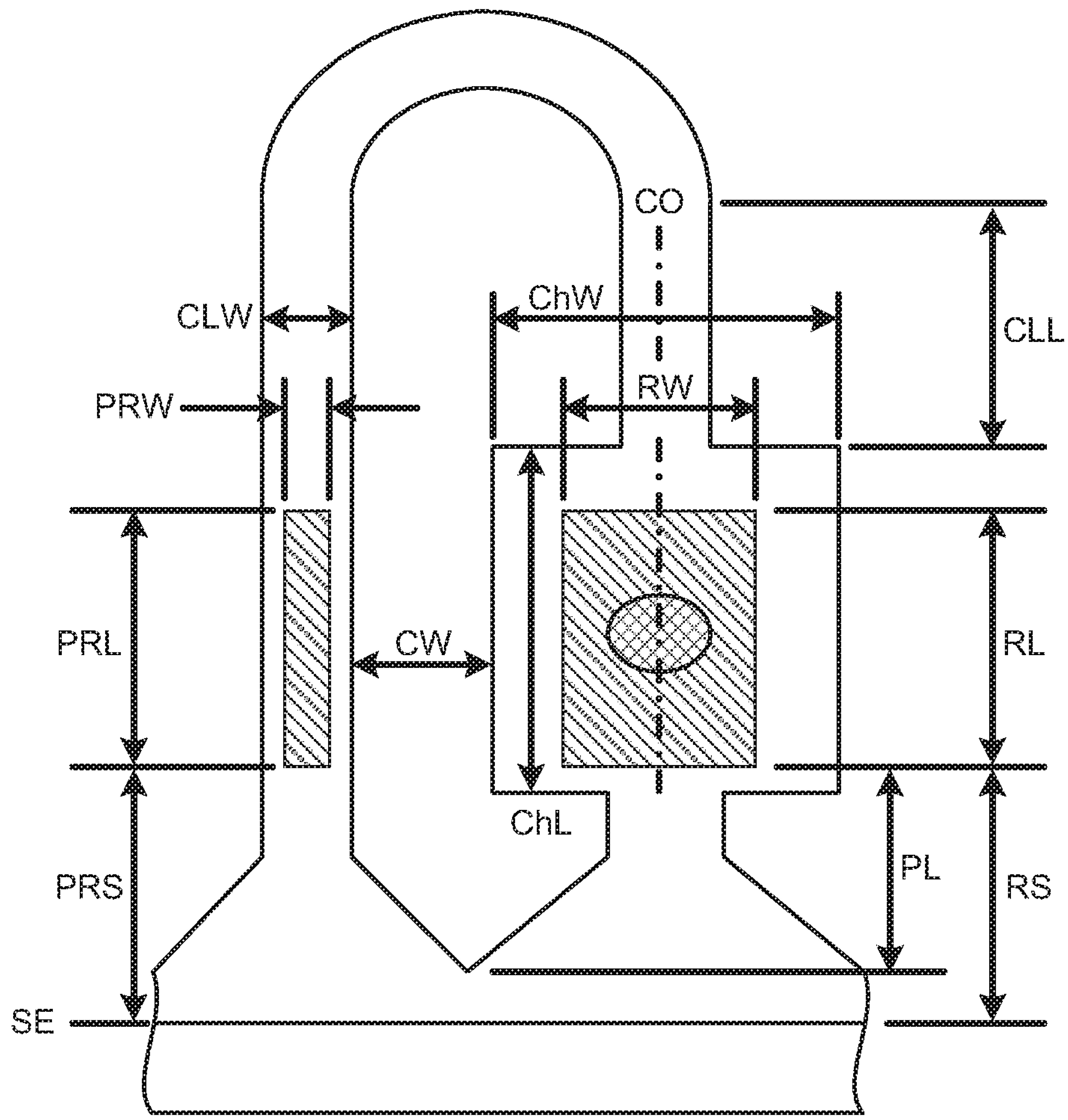

FIG. 2B

	Lower Level (μm)	Upper Level (μm)
Main Resistor Width (RW)	10	22
Main Resistor Length (RL)	10	>60
Main Resistor Shelf Length (RS)	0	>60
Pump Resistor Width (PRW)	2	14
Pump Resistor Length (PRL)	5	50
Pump Resistor Shelf Length (PRS)	near 0	>60
Main Resistor Chamber Width (ChW)	14	26
Main Resistor Chamber Length (ChL)	12	>62
Circulation Channel Loop Width (CLW)	5	16
Circulation Channel Loop Length (CLL)	0	~500
Circulation Channel Offset (CO)	0	±11
Channel Wall Width (CW)	5	11
Peninsula Length (PL)	0	>>80

FIG. 3

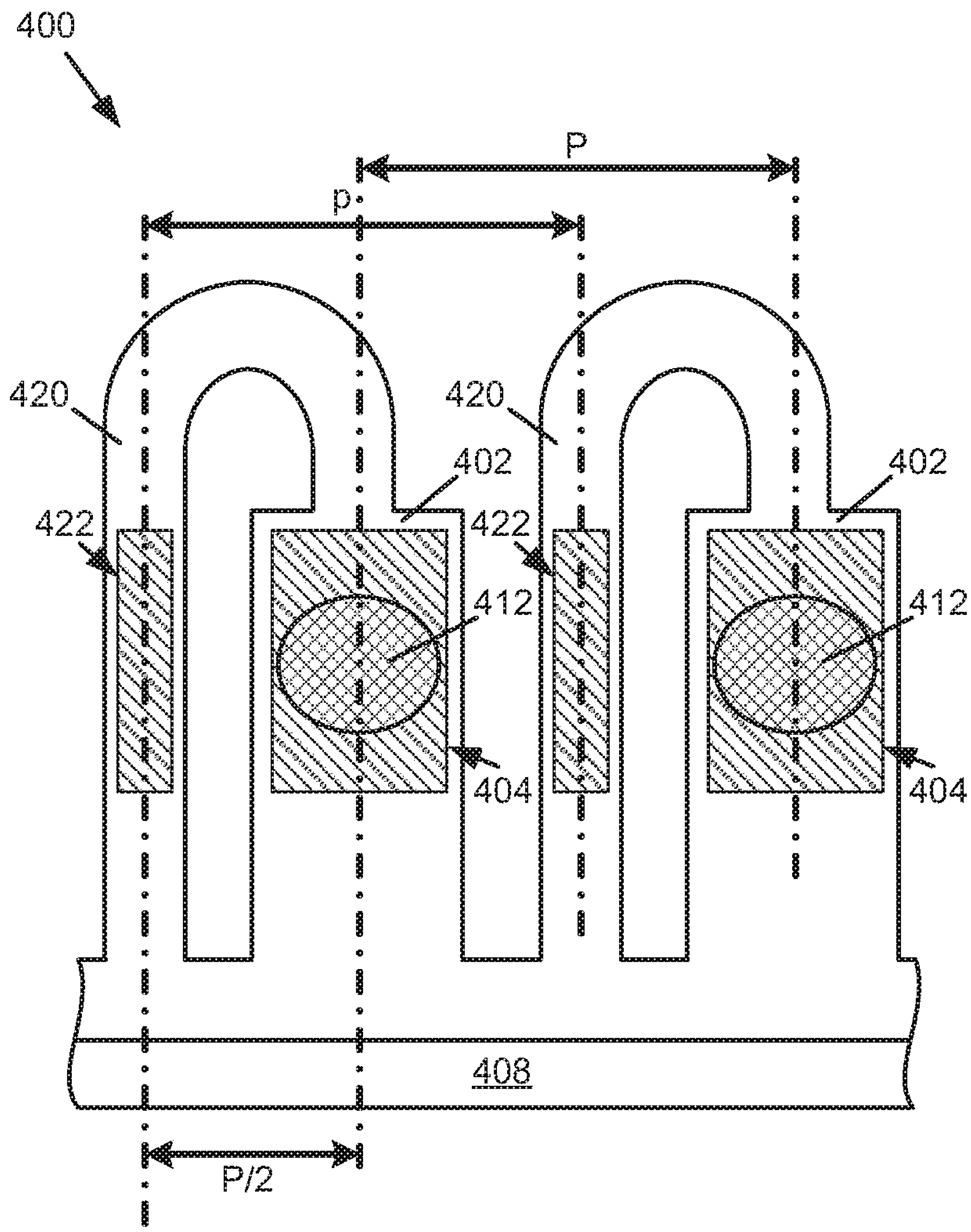

FIG. 4

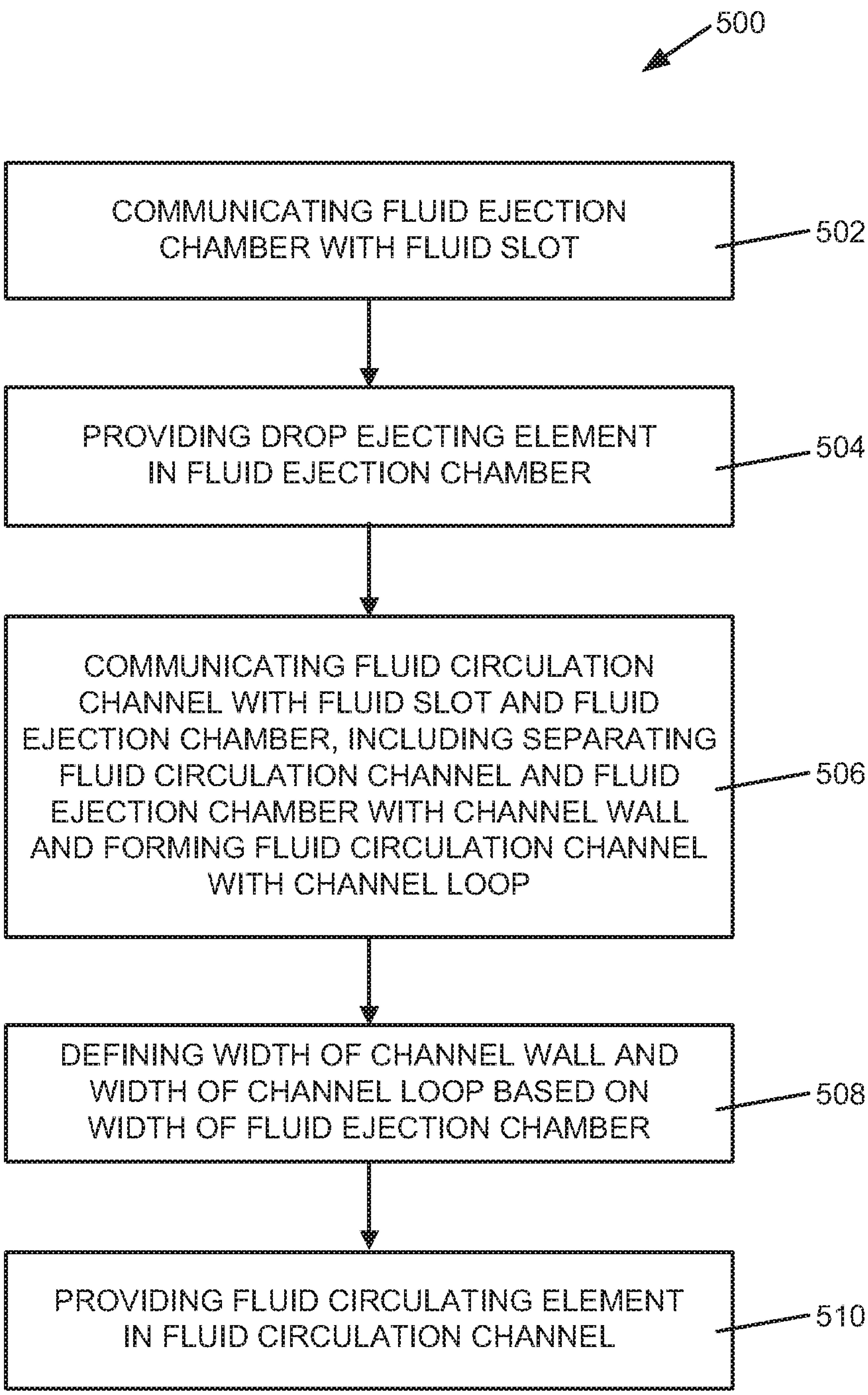
500
COMMUNICATING FLUID EJECTION CHAMBER WITH FLUID SLOT
502
PROVIDING DROP EJECTING ELEMENT IN FLUID EJECTION CHAMBER
504
COMMUNICATING FLUID CIRCULATION CHANNEL WITH FLUID SLOT AND FLUID EJECTION CHAMBER, INCLUDING SEPARATING FLUID CIRCULATION CHANNEL AND FLUID EJECTION CHAMBER WITH CHANNEL WALL AND FORMING FLUID CIRCULATION CHANNEL WITH CHANNEL LOOP
506
DEFINING WIDTH OF CHANNEL WALL AND WIDTH OF CHANNEL LOOP BASED ON WIDTH OF FLUID EJECTION CHAMBER
508
PROVIDING FLUID CIRCULATING ELEMENT IN FLUID CIRCULATION CHANNEL
510

FIG. 5

FLUID EJECTION DEVICE

BACKGROUND

Fluid ejection devices, such as printheads in inkjet printing systems, may use thermal resistors or piezoelectric material membranes as actuators within fluidic chambers to eject fluid drops (e.g., ink) from nozzles, such that properly sequenced ejection of ink drops from the nozzles causes characters or other images to be printed on a print medium as the printhead and the print medium move relative to each other.

Decap is the amount of time inkjet nozzles can remain uncapped and exposed to ambient conditions without causing degradation in ejected ink drops. Effects of decap can alter drop trajectories, velocities, shapes and colors, all of which can negatively impact print quality. Other factors related to decap, such as evaporation of water or solvent, can cause pigment-ink vehicle separation (PIVS) and viscous ink plug formation. For example, during periods of storage or non-use, pigment particles can settle or "crash" out of the ink vehicle which can impede or block ink flow to the ejection chambers and nozzles.

BRIEF DESCRIPTION OF THE DRAWINGS

FIG. **1** is a block diagram illustrating one example of an inkjet printing system including an example of a fluid ejection device.

FIGS. **2**A and **2**B are schematic plan views illustrating one example of a portion of a fluid ejection device.

FIG. **3** is a table outlining example parameters and example ranges of the parameters of a fluid ejection device.

FIG. **4** is a schematic plan view illustrating one example of a portion of a fluid ejection device.

FIG. **5** is a flow diagram illustrating one example of a method of forming a fluid ejection device.

DETAILED DESCRIPTION

In the following detailed description, reference is made to the accompanying drawings which form a part hereof, and in which is shown by way of illustration specific examples in which the disclosure may be practiced. It is to be understood that other examples may be utilized and structural or logical changes may be made without departing from the scope of the present disclosure.

The present disclosure helps to reduce ink blockage and/or clogging in inkjet printing systems generally by circulating (or recirculating) fluid through fluid ejection chambers. Fluid circulates (or recirculates) through fluidic channels that include fluid circulating elements or actuators to pump or circulate the fluid.

FIG. **1** illustrates one example of an inkjet printing system as an example of a fluid ejection device with fluid circulation, as disclosed herein. Inkjet printing system **100** includes a printhead assembly **102**, an ink supply assembly **104**, a mounting assembly **106**, a media transport assembly **108**, an electronic controller **110**, and at least one power supply **112** that provides power to the various electrical components of inkjet printing system **100**. Printhead assembly **102** includes at least one fluid ejection assembly **114** (printhead **114**) that ejects drops of ink through a plurality of orifices or nozzles **116** toward a print medium **118** so as to print on print media **118**.

Print media **118** can be any type of suitable sheet or roll material, such as paper, card stock, transparencies, Mylar, and the like. Nozzles **116** are typically arranged in one or more columns or arrays such that properly sequenced ejection of ink from nozzles **116** causes characters, symbols, and/or other graphics or images to be printed on print media **118** as printhead assembly **102** and print media **118** are moved relative to each other.

Ink supply assembly **104** supplies fluid ink to printhead assembly **102** and, in one example, includes a reservoir **120** for storing ink such that ink flows from reservoir **120** to printhead assembly **102**. Ink supply assembly **104** and printhead assembly **102** can form a one-way ink delivery system or a recirculating ink delivery system. In a one-way ink delivery system, substantially all of the ink supplied to printhead assembly **102** is consumed during printing. In a recirculating ink delivery system, only a portion of the ink supplied to printhead assembly **102** is consumed during printing. Ink not consumed during printing is returned to ink supply assembly **104**.

In one example, printhead assembly **102** and ink supply assembly **104** are housed together in an inkjet cartridge or pen. In another example, ink supply assembly **104** is separate from printhead assembly **102** and supplies ink to printhead assembly **102** through an interface connection, such as a supply tube. In either example, reservoir **120** of ink supply assembly **104** may be removed, replaced, and/or refilled. Where printhead assembly **102** and ink supply assembly **104** are housed together in an inkjet cartridge, reservoir **120** includes a local reservoir located within the cartridge as well as a larger reservoir located separately from the cartridge. The separate, larger reservoir serves to refill the local reservoir. Accordingly, the separate, larger reservoir and/or the local reservoir may be removed, replaced, and/or refilled.

Mounting assembly **106** positions printhead assembly **102** relative to media transport assembly **108**, and media transport assembly **108** positions print media **118** relative to printhead assembly **102**. Thus, a print zone **122** is defined adjacent to nozzles **116** in an area between printhead assembly **102** and print media **118**. In one example, printhead assembly **102** is a scanning type printhead assembly. As such, mounting assembly **106** includes a carriage for moving printhead assembly **102** relative to media transport assembly **108** to scan print media **118**. In another example, printhead assembly **102** is a non-scanning type printhead assembly. As such, mounting assembly **106** fixes printhead assembly **102** at a prescribed position relative to media transport assembly **108**. Thus, media transport assembly **108** positions print media **118** relative to printhead assembly **102**.

Electronic controller **110** typically includes a processor, firmware, software, one or more memory components including volatile and no-volatile memory components, and other printer electronics for communicating with and controlling printhead assembly **102**, mounting assembly **106**, and media transport assembly **108**. Electronic controller **110** receives data **124** from a host system, such as a computer, and temporarily stores data **124** in a memory. Typically, data **124** is sent to inkjet printing system **100** along an electronic, infrared, optical, or other information transfer path. Data **124** represents, for example, a document and/or file to be printed. As such, data **124** forms a print job for inkjet printing system **100** and includes one or more print job commands and/or command parameters.

In one example, electronic controller **110** controls printhead assembly **102** for ejection of ink drops from nozzles **116**. Thus, electronic controller **110** defines a pattern of ejected ink drops which form characters, symbols, and/or other graphics or images on print media **118**. The pattern of ejected ink drops is determined by the print job commands and/or command parameters.

Printhead assembly **102** includes one or more printheads **114**. In one example, printhead assembly **102** is a wide-array or multi-head printhead assembly. In one implementation of a wide-array assembly, printhead assembly **102** includes a carrier that carries a plurality of printheads **114**, provides electrical communication between printheads **114** and electronic controller **110**, and provides fluidic communication between printheads **114** and ink supply assembly **104**.

In one example, inkjet printing system **100** is a drop-on-demand thermal inkjet printing system wherein printhead **114** is a thermal inkjet (TIJ) printhead. The thermal inkjet printhead implements a thermal resistor ejection element in an ink chamber to vaporize ink and create bubbles that force ink or other fluid drops out of nozzles **116**. In another example, inkjet printing system **100** is a drop-on-demand piezoelectric inkjet printing system wherein printhead **114** is a piezoelectric inkjet (PIJ) printhead that implements a piezoelectric material actuator as an ejection element to generate pressure pulses that force ink drops out of nozzles **116**.

In one example, electronic controller **110** includes a flow circulation module **126** stored in a memory of controller **110**. Flow circulation module **126** executes on electronic controller **110** (i.e., a processor of controller **110**) to control the operation of one or more fluid actuators integrated as pump elements within printhead assembly **102** to control circulation of fluid within printhead assembly **102**.

FIG. **2**A is a schematic plan view illustrating one example of a portion of a fluid ejection device **200**. Fluid ejection device **200** includes a fluid ejection chamber **202** and a corresponding drop ejecting element **204** formed or provided within fluid ejection chamber **202**. Fluid ejection chamber **202** and drop ejecting element **204** are formed on a substrate **206** which has a fluid (or ink) feed slot **208** formed therein such that fluid feed slot **208** provides a supply of fluid (or ink) to fluid ejection chamber **202** and drop ejecting element **204**. Substrate **206** may be formed, for example, of silicon, glass, or a stable polymer.

In one example, fluid ejection chamber **202** is formed in or defined by a barrier layer **210** provided on substrate **206**. As such, fluid ejection chamber **202** includes opposite end walls **202***a* and **202***b*, and opposite sidewalls **202***c* and **202***d* such that fluid ejection chamber **202** provides a "well" in barrier layer **210**. Barrier layer **210** may be formed, for example, of a photoimageable epoxy resin, such as SU8.

In one example, a nozzle or orifice layer (not shown) is formed or extended over barrier layer **210** such that a nozzle opening or orifice **212** formed in the orifice layer communicates with a respective fluid ejection chamber **202**. Nozzle opening or orifice **212** may be of a circular, non-circular, or other shape.

Drop ejecting element **204** can be any device capable of ejecting fluid drops through corresponding nozzle opening or orifice **212**. Examples of drop ejecting element **204** include a thermal resistor or a piezoelectric actuator. A thermal resistor, as an example of a drop ejecting element, is typically formed on a surface of a substrate (substrate **206**), and includes a thin-film stack including an oxide layer, a metal layer, and a passivation layer such that, when activated, heat from the thermal resistor vaporizes fluid in fluid ejection chamber **202**, thereby causing a bubble that ejects a drop of fluid through nozzle opening or orifice **212**. A piezoelectric actuator, as an example of a drop ejecting element, generally includes a piezoelectric material provided on a moveable membrane communicated with fluid ejection chamber **202** such that, when activated, the piezoelectric material causes deflection of the membrane relative to fluid ejection chamber **202**, thereby generating a pressure pulse that ejects a drop of fluid through nozzle opening or orifice **212**.

As illustrated in the example of FIG. **2**A, fluid ejection device **200** includes a fluid circulation channel **220** and a fluid circulating element **222** formed in, provided within, or communicated with fluid circulation channel **220**. Fluid circulation channel **220** is open to and communicates at one end **224** with fluid feed slot **208** and communicates at another end **226** with fluid ejection chamber **202** such that fluid from fluid feed slot **208** circulates (or recirculates) through fluid circulation channel **220** and fluid ejection chamber **202** based on flow induced by fluid circulating element **222**.

In the example illustrated in FIG. **2**A, fluid circulation channel **220** is a U-shaped channel and includes a channel loop portion **228**. As such, end **226** of fluid circulation channel **220** communicates with fluid ejection chamber **202** at end wall **202***a* of fluid ejection chamber **202**.

In one example, fluid ejection chamber **202** and fluid circulation channel **220** are separated by a channel wall **230**. In one example, a peninsula **232** extends from channel wall **230** toward fluid feed slot **208**. In one example, channel wall **230** and peninsula **232** are formed by barrier layer **210** such that fluid circulation channel **220** is formed in or defined by barrier layer **210**.

In the example illustrated in FIG. **2**A, drop ejecting element **204** and fluid circulating element **222** are both thermal resistors. Each of the thermal resistors may include, for example, a single resistor, a split resistor, a comb resistor, or multiple resistors. A variety of other devices, however, can also be used to implement drop ejecting element **204** and fluid circulating element **222** including, for example, a piezoelectric actuator, an electrostatic (MEMS) membrane, a mechanical/impact driven membrane, a voice coil, a magneto-strictive drive, and so on. As referenced below, the thermal resistor of drop ejecting element **204** is referred to as main resistor **205**, and the thermal resistor of fluid circulating element **222** is referred to as pump resistor **223**.

FIG. **2**B is a schematic plan view illustrating one example of parameters of fluid ejection device **200**. In one example, and as outlined in the table of FIG. **3**, various parameters of fluid ejection device **200** are selected or defined to optimize performance of fluid ejection device **200**.

With reference to FIGS. **2**A and **2**B, various parameters of fluid ejection device **200** are identified as follows:

RW—main resistor width
RL—main resistor length
RS—main resistor shelf length
PRW—pump resistor width
PRL—pump resistor length
PRS—pump resistor shelf length
ChW—main resistor chamber width
ChL—main resistor chamber length
CLW—circulation channel loop width
CLL—circulation channel loop length
CO—circulation channel offset
CW—channel wall width
PL—peninsula length
SE—fluid slot edge

Notably, the main resistor shelf length (RS) and the pump resistor shelf length (PRS) are defined as a distance from the edge of main resistor **205** and the edge of pump resistor **223**, respectively, to the edge (SE) of fluid feed slot **208**.

Although the main resistor shelf length (RS) and the pump resistor shelf length (PRS) are illustrated as being the same, the main resistor shelf length (RS) and the pump resistor shelf length (PRS) may vary from each other. In addition, while fluid ejection chamber **202** is illustrated as being rectangular in shape, fluid ejection chamber **202** may be of other shapes.

In one example, the circulation channel loop width (CLW) of fluid circulation channel **220** is substantially uniform from and to and between end **224** and end **226**. In addition, the circulation channel loop length (CLL) is defined as a distance from end wall **202***a* of fluid ejection chamber **202** to a point of curvature of channel loop portion **228** of fluid circulation channel **220**. Furthermore, the circulation channel offset (CO) is defined as a distance between a centerline or axis of symmetry **203** of fluid ejection chamber **202** and a centerline or axis of symmetry **221** of fluid circulation channel **220**. As illustrated in the example of FIG. **2**B, the circulation channel offset (CO) is zero (0) such that fluid circulation channel **220** is axisymmetrical with fluid ejection chamber **202**. The circulation channel offset (CO), however, may vary as end **226** of fluid circulation channel **220** is positioned along end wall **202***a* of fluid ejection chamber **202**.

Channel wall width (CW) is defined as a distance between fluid ejection chamber **202** and fluid circulation channel **220**. More specifically, in one example, channel wall width (CW) is defined as a distance between sidewall **202***c* of fluid ejection chamber **202** and a sidewall of a portion of fluid circulation channel **220** in which pump resistor **223** is positioned. As such, and as illustrated in the examples of FIGS. **2**A and **2**B, channel wall width (CW) is measured in a direction substantially perpendicular to the axis of symmetry **203** of fluid ejection chamber **202**. Furthermore, peninsula length (PL) is defined as a distance from an end of main resistor **205** (namely, an end of main resistor **205** closest to fluid feed slot **208**) to an end of peninsula **232** (namely, an end of peninsula **232** closest to fluid feed slot **208**).

FIG. **3** is a table outlining example ranges, more specifically, lower levels and upper levels of parameters of fluid ejection device **200**. In one example, channel wall width (CW) is based on circulation channel loop width (CLW) and main resistor chamber width (ChW), and circulation channel loop width (CLW) is based on channel wall width (CW) and main resistor chamber width (ChW). As such, channel wall width (CW) and circulation channel loop width (CLW) are both based on main resistor chamber width (ChW).

More specifically, in one example, channel wall width (CW) is defined by the following equation:

$$CW=(42-CLW-ChW)/2$$

where CLW=circulation channel loop width (microns), and ChW=main resistor chamber width (microns).

In addition, in one example, circulation channel loop width (CLW) is defined by the following equation:

$$CLW=42-2CW-ChW$$

where CW=channel wall width (microns), and ChW=main resistor chamber width (microns).

FIG. **4** is a schematic plan view illustrating one example of a portion of a fluid ejection device **400**. Fluid ejection device **400** includes a plurality of fluid ejection chambers **402** and a plurality of fluid circulation channels **420**. Similar to that described above, fluid ejection chambers **402** each include a drop ejecting element **404** with a corresponding nozzle opening or orifice **412**, and fluid circulation channels **420** each include a fluid circulating element **422**.

In one example, fluid ejection chambers **402**, including associated drop ejecting elements **404** with corresponding nozzle openings or orifices **412**, and fluid circulation channels **420**, including associated fluid circulating elements **422**, are evenly arranged, or are an equal distance apart from one another, along a length of fluid feed slot **408**. More specifically, in one example, a distance or pitch P between adjacent drop ejecting elements **404** (and corresponding nozzle openings or orifices **412**) is substantially equal to a distance or pitch p between adjacent fluid circulating elements **422**. In addition, in one example, a distance or spacing between a drop ejecting element **404** and an associated fluid circulating element **422** is approximately one-half of pitch P between adjacent drop ejecting elements **404** (namely, P/2).

As illustrated in the examples of FIGS. **2**A, **2**B, and FIG. **4**, each fluid circulation channel **220**, **420** communicates with one (i.e., a single) fluid ejection chamber **202**, **402**. As such, fluid ejection devices **200** and **400** each have a 1:1 nozzle-to-pump ratio. With a 1:1 ratio, circulation is individually provided for each fluid ejection chamber **202**, **402**, thereby enabling efficient circulation servicing of every nozzle.

FIG. **5** is a flow diagram illustrating one example of a method **500** of forming a fluid ejection device, such as fluid ejection device **200** as illustrated in the examples of FIGS. **2**A and **2**B.

At **502**, method **500** includes communicating a fluid ejection chamber, such as fluid ejection chamber **202**, with a fluid slot, such as fluid feed slot **208**.

At **504**, method **500** includes providing a drop ejecting element, such as drop ejecting element **204**, in the fluid ejection chamber, such as fluid ejection chamber **202**.

At **506**, method **500** includes communicating a fluid circulation channel, such as fluid circulation channel **220**, with the fluid slot and the fluid ejection chamber, such as fluid feed slot **208** and fluid ejection chamber **202**. In this regard, **506** of method **500** includes separating the fluid circulation channel, such as fluid circulation channel **220**, and the fluid ejection chamber, such as fluid ejection chamber **202**, with a channel wall, such as channel wall **230**, and forming the fluid circulation channel, such as fluid circulation channel **220**, with a channel loop, such as channel loop portion **228**.

At **508**, method **500** includes defining a width of the channel wall, such as channel wall width (CW), and a width of the channel loop, such as circulation channel loop width (CLW), based on a width of the fluid ejection chamber, such as main resistor chamber width (ChW).

At **510**, method **500** includes providing a fluid circulating element, such as fluid circulating element **222**, in the fluid circulation channel, such as fluid circulation channel **220**.

Although illustrated and described as separate and/or sequential steps, the method of forming the fluid ejection device may include a different order or sequence of steps, and may combine one or more steps or perform one or more steps concurrently, partially or wholly.

With a fluid ejection device including circulation as described herein, ink blockage and/or clogging is reduced. As such, decap time and, therefore, nozzle health are improved. In addition, pigment-ink vehicle separation and viscous ink plug formation are reduced or eliminated. Furthermore, ink efficiency is improved by lowering ink consumption during servicing (e.g., minimizing spitting of ink to keep nozzles healthy). In addition, a fluid ejection device including circulation as described herein, helps to manage air bubbles by purging air bubbles from the ejection chamber during circulation.

Although specific examples have been illustrated and described herein, it will be appreciated by those of ordinary skill in the art that a variety of alternate and/or equivalent implementations may be substituted for the specific examples shown and described without departing from the scope of the present disclosure. This application is intended to cover any adaptations or variations of the specific examples discussed herein.

What is claimed is:

1. A fluid ejection device, comprising:
- a fluid slot;
- a fluid ejection chamber communicated with the fluid slot;
- a drop ejecting element within the fluid ejection chamber;
- a fluid circulation channel communicated at one end with the fluid slot and communicated at another end with the fluid ejection chamber;
- a fluid circulating element within the fluid circulation channel; and
- a channel wall separating the fluid ejection chamber and the fluid circulation channel, the channel wall defined as a distance between a sidewall of the fluid ejection chamber and a sidewall of a portion of the fluid circulation channel in which the fluid circulating element is positioned,
- wherein the fluid circulation channel includes a channel loop, and
- wherein a width of the channel wall is defined based on a width of the channel loop and a width of the fluid ejection chamber.

2. The fluid ejection device of claim **1**, wherein the width of the channel wall is defined as CW=(42−CLW−ChW)/2, wherein CLW is a width of the channel loop, and ChW is a width of the fluid ejection chamber.

3. The fluid ejection device of claim **2**, wherein the width of the channel wall is in a range of approximately 5 microns to approximately 11 microns.

4. The fluid ejection device of claim **3**, wherein the width of the channel loop is in a range of approximately 5 microns to approximately 16 microns, and the width of the fluid ejection chamber is in a range of approximately 14 microns to approximately 26 microns.

5. The fluid ejection device of claim **1**, wherein the fluid ejection device includes a plurality of fluid ejection chambers and corresponding drop ejecting elements, and a plurality of fluid circulation channels and corresponding fluid circulating elements, wherein each fluid circulation channel communicates with a single fluid ejection chamber.

6. The fluid ejection device of claim **5**, wherein a pitch of adjacent fluid circulating elements is substantially equal to a pitch of adjacent drop ejecting elements.

7. The fluid ejection device of claim **6**, wherein a spacing between a drop ejecting element and an associated fluid circulating element is approximately one-half of the pitch of adjacent drop ejecting elements.

8. The fluid ejection device of claim **1**, wherein the fluid ejection chamber is formed in a barrier layer provided on a substrate.

9. The fluid ejection device of claim **1**, wherein a main resistor shelf length defined as a distance from a main resistor and an edge of the fluid slot and a pump resistor shelf length defined as a distance from an edge of the fluid circulating element to the edge of the fluid slot are different lengths.

10. The fluid ejection device of claim **9**, wherein the main resistor shelf length is between 0 and 60 microns.

11. The fluid ejection device of claim **9**, wherein the pump resistor shelf length is between 0 and 60 microns.

12. The fluid ejection device of claim **1**, wherein a peninsula extending from the channel wall towards the fluid slot has a length less than 80 microns.

13. A fluid ejection device, comprising:
- a fluid slot;
- a fluid ejection chamber communicated with the fluid slot;
- a drop ejecting element within the fluid ejection chamber;
- a fluid circulation channel communicated at one end with the fluid slot and communicated at another end with the fluid ejection chamber; and
- a fluid circulating element within the fluid circulation channel,
- wherein the fluid circulation channel includes a channel loop, and
- wherein a width of the channel loop is selected based on a spacing between the fluid circulation channel and the fluid ejection chamber, and a width of the fluid ejection chamber.

14. The fluid ejection device of claim **13**, wherein the width of the channel loop is defined as 42−2CW−ChW, wherein CW is the spacing between the fluid circulation channel and the fluid ejection chamber, and ChW is the width of the fluid ejection chamber.

15. The fluid ejection device of claim **14**, wherein the width of the channel loop is in a range of approximately 5 microns to approximately 16 microns.

16. The fluid ejection device of claim **15**, wherein the spacing between the fluid circulation channel and the fluid ejection chamber is in a range of approximately 5 microns to approximately 11 microns, and the width of the fluid ejection chamber is in a range of approximately 14 microns to approximately 26 microns.

17. A method of forming the fluid ejection device of claim **1**, comprising:
- communicating the fluid ejection chamber with the fluid slot;
- providing the drop ejecting element in the fluid ejection chamber;
- communicating the fluid circulation channel with the fluid slot and the fluid ejection chamber, including separating the fluid circulation channel and the fluid ejection chamber with the channel wall and forming the fluid circulation channel with the channel loop;
- defining the width of the channel wall and the width of the channel loop based on the width of the fluid ejection chamber; and
- providing the fluid circulating element in the fluid circulation channel.

18. The method of claim **17**, wherein the width of the channel wall is in a range of approximately 5 microns to approximately 11 microns, wherein the width of the channel loop is in a range of approximately 5 microns to approximately 16 microns, and wherein the width of the fluid ejection chamber is in a range of approximately 14 microns to approximately 26 microns.

19. The method of claim **18**, wherein the width of the channel wall is defined as CW=(42−CLW−ChW)/2, wherein CLW is a width of the channel loop, and ChW is a width of the fluid ejection chamber.

20. The method of claim **18**, wherein the width of the channel loop is defined as 42−2CW−ChW, wherein CW is the spacing between the fluid circulation channel and the fluid ejection chamber, and ChW is the width of the fluid ejection chamber.

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